

ABSTRACT

TEST HANDLER TEMPERATURE MONITORING SYSTEM

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The invention provides a temperature monitoring system for a semiconductor test handler. A preparation stage brings a test device to a predetermined temperature for testing at a test platform at said predetermined temperature.

10 At least one radiation sensor, such as a thermopile device, is employed in the test handler for detecting a surface temperature of the test device by measuring radiation emitted from the test device.

(Fig. 2)